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Sheet 1 of 2

Form PTO-1449 (Substitute)

U.S. SEPARTMENT OF COMMERCE

Information Disclosure Statement
BY APPLICANT
(Use several sheets if necessary)

Attorney Docket Number TEGL-01168US0	Application/Patent Number 10/636,020	
Applicant/Patent Owner Tue Nguyen		
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Filing/Issue Date Group Art Unit
August 7, 2003 1734

Filing Examiner Inventor(s) Class Subclass Date Patent Number Issue Date Initial 05/1970 Hablanian et al. 3,514,391 5,804,046 09/1998 Sawada et al. 11/1998 Koyama et al. 5,837,057 07/1977 Alexander, Jr. et al. 4,033,287 5,277,751 01/1994 Ogle 05/1995 Nishibayashi et al. 5,417,798 08/1995 Kojima et al. 5,445,709 04/1996 Sablev et al. 5,503,725

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Examiner Date Considered 5/06								
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